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				Application Number	10/765,904	
INFO	RMATION	DISCLOS	URE	Confirmation Number	2613	
		Y APPLIC		Filing Date	January 29, 2004	
				First Named Inventor	Markus MENGEL	
(use	as many she	ets as necessai	y)	Art Unit	Not Yet Assigned	
·				Examiner Name	Not Yet Assigned	_
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^{&#}x27;Applicant's unique citation designation number (optional). ²See Kind Codes of USPTO Patent Documents at www.uspto.gov, MPEP 901.04 or in the comment box of this document. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST. 3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ³Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to indicate here if English language Translation is attached.

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INFO	RMATION	DISCLOS	SURE	Confirmation Number	Not Yet Assigned	
STAT	EMENT BY	APPLIC	ANT	Filing Date	January 29, 2004	
				First Named Inventor	Markus MENGEL	
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